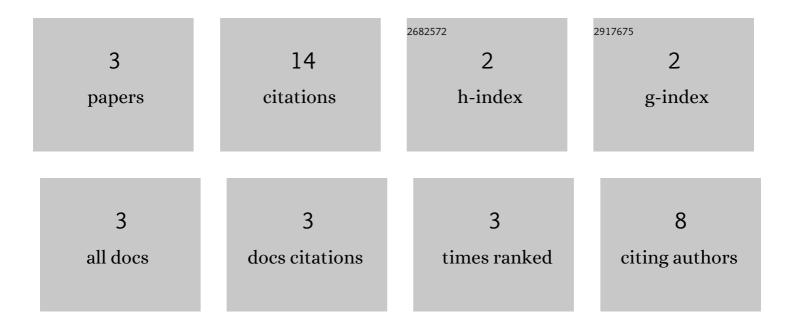
## David van den Hurk

List of Publications by Year in descending order

Source: https://exaly.com/author-pdf/6098317/publications.pdf Version: 2024-02-01



#	Article	IF	CITATIONS
1	Performance-Based Active Wafer Clamp Design for Wafer Heating Effects in EUV Lithography. IEEE Transactions on Semiconductor Manufacturing, 2020, 33, 424-432.	1.7	5
2	Control of Thermo-Mechanical Wafer Deformations in EUV Lithography Using an Active Wafer Clamp. IEEE Transactions on Semiconductor Manufacturing, 2020, 33, 96-102.	1.7	2
3	Modeling and localized feedforward control of thermal deformations induced by a moving heat load. , 2018, , .		7